

5th June 2023

**EPIC Technology Meeting:  
Photonic Integration and Packaging at Fraunhofer IZM**

# Scaling up the photonic testing back-end

---

**HITACHI**  
Inspire the Next

**VLC**  
**PHOTONICS**  
A Hitachi Group Company

# About us

- ❑ VLC Photonics offers Photonic Integrated Circuit (PIC) engineering services, focused on design and testing.
- ❑ Company founded in 2011.
- ❑ Offices and clean-room labs in Valencia Technological Campus (Spain).
- ❑ 28 members of extensive academic and industrial experience, and keep hiring.
- ❑ Part of Hitachi High-Tech group since 2020.



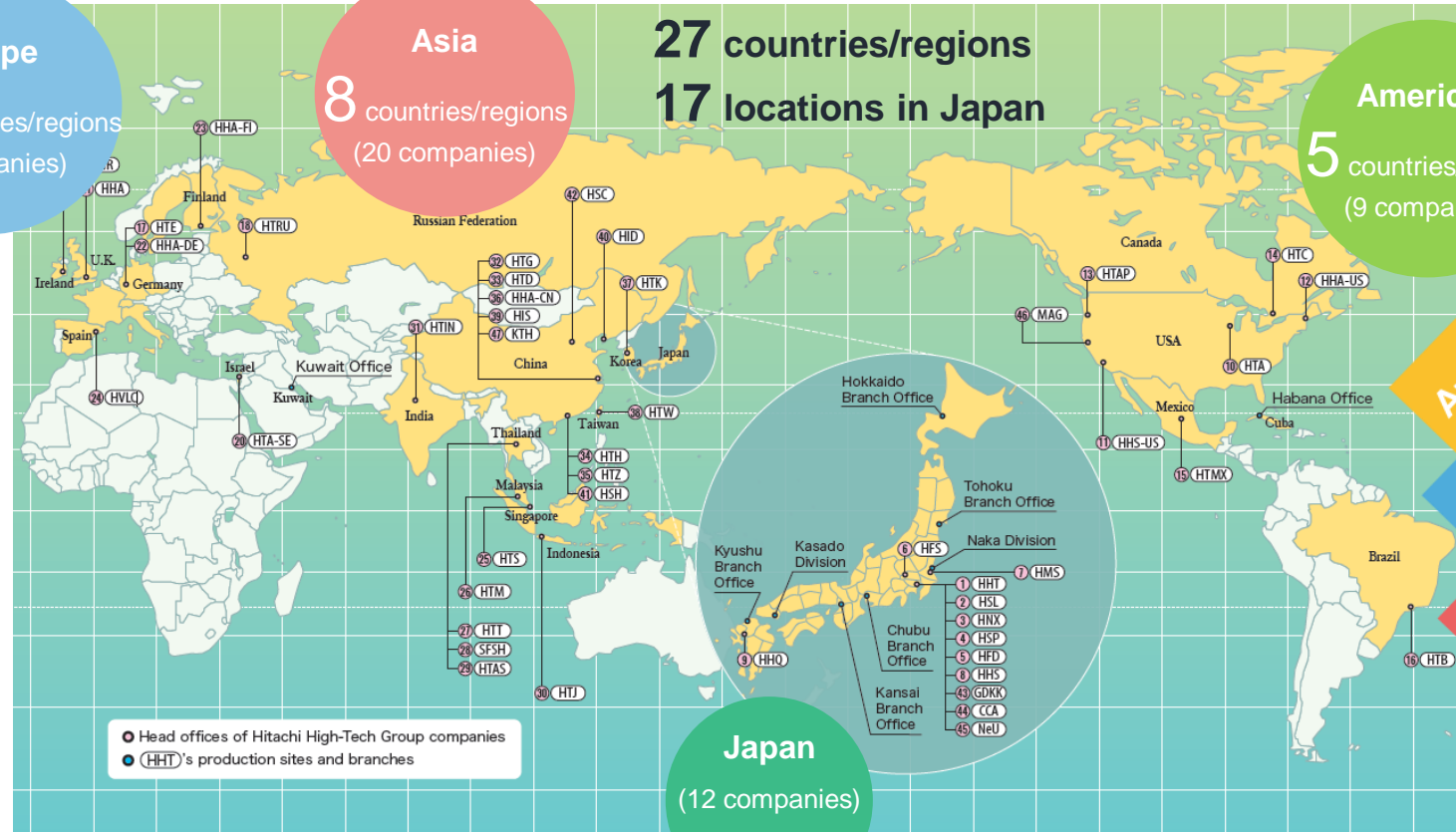
## Hitachi High-Tech Corporation

**Europe**  
11 countries/regions  
(7 companies)

**Asia**  
8 countries/regions  
(20 companies)

**27 countries/regions**  
**17 locations in Japan**

**Americas**  
5 countries/regions  
(9 companies)

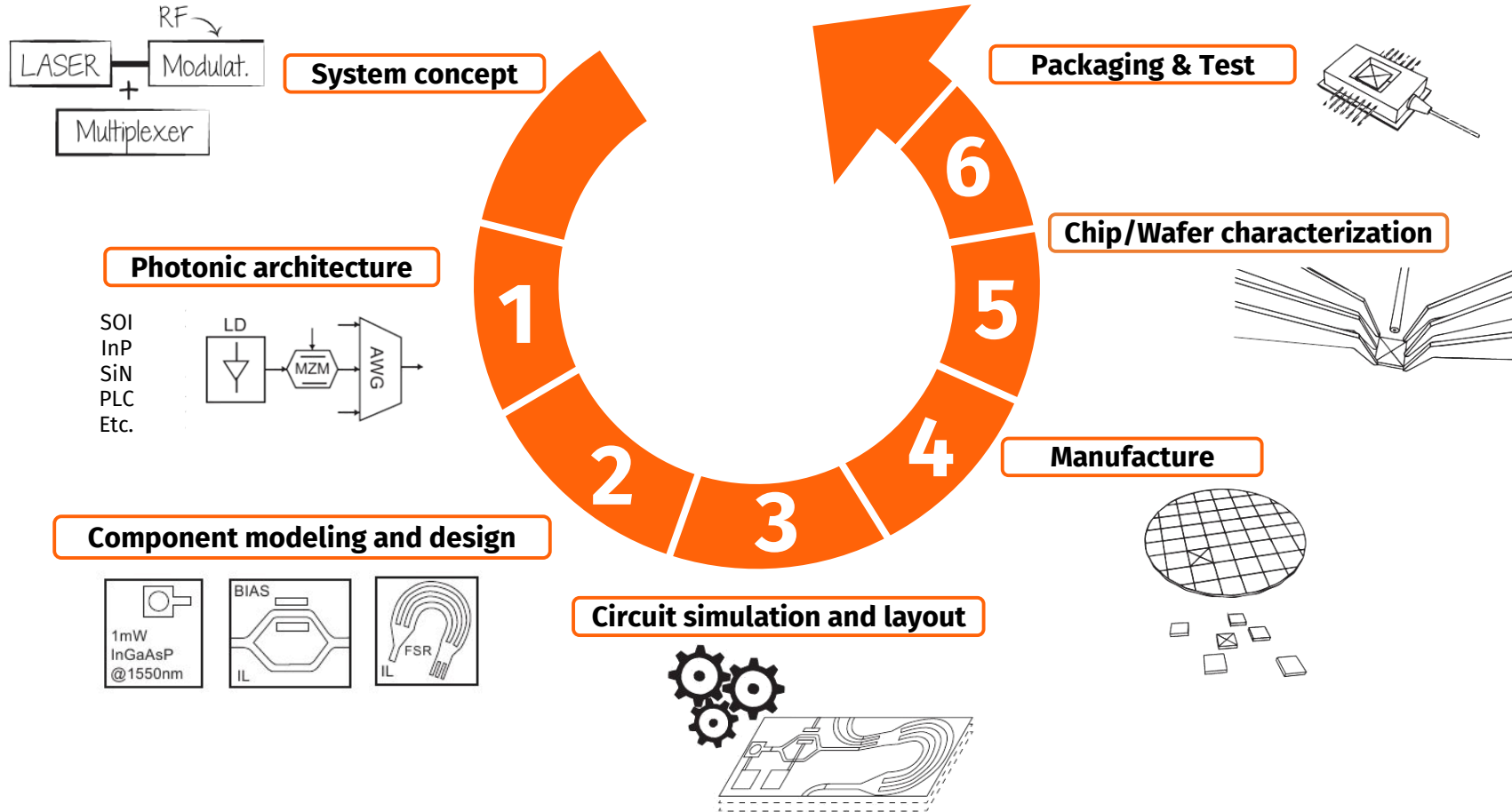


Analytical & Medical Solutions  
Nano-Technology Solutions  
Industrial Solutions

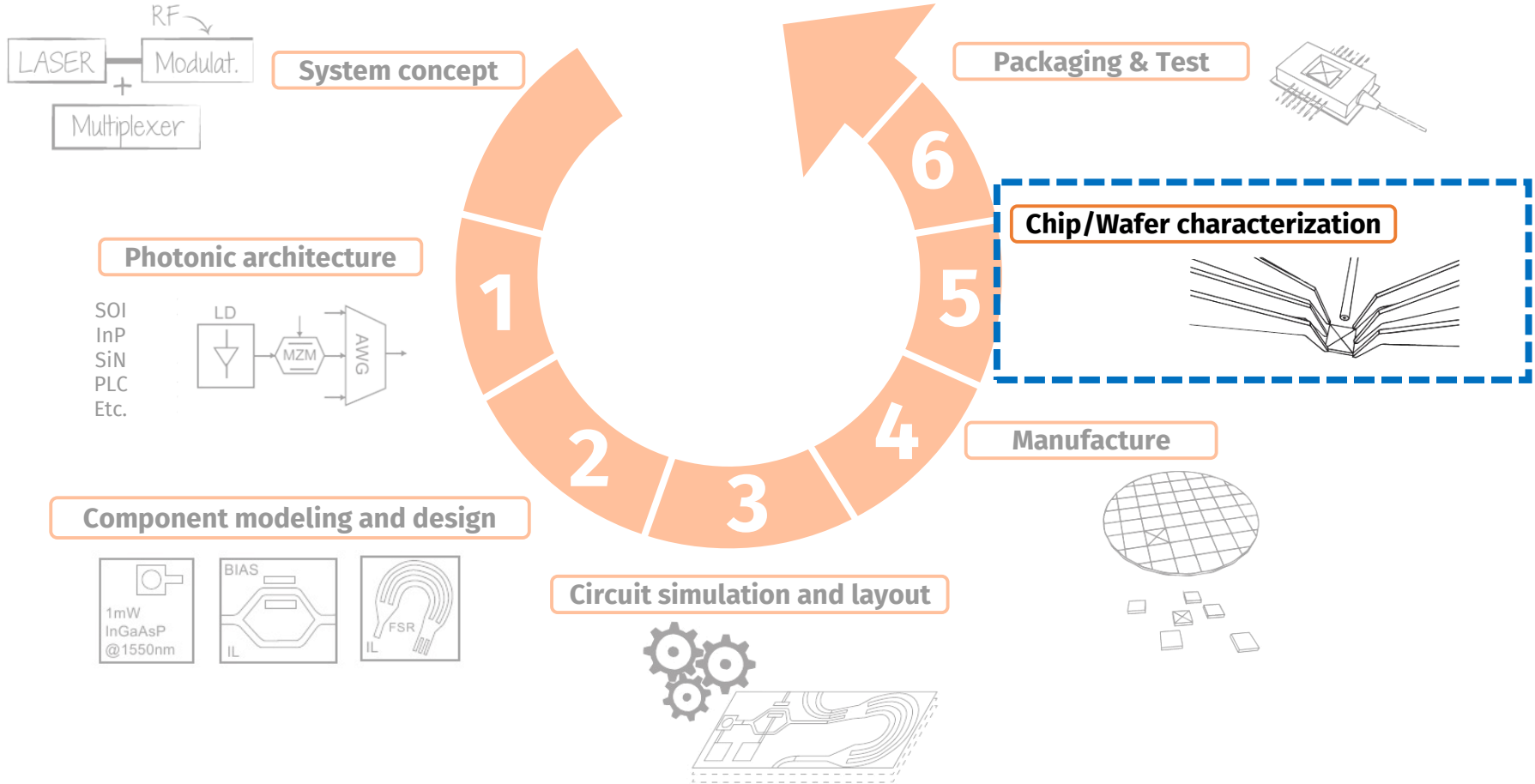
**VLC**  
PHOTONICS  
A Hitachi Group Company

**Provision of PIC solutions**

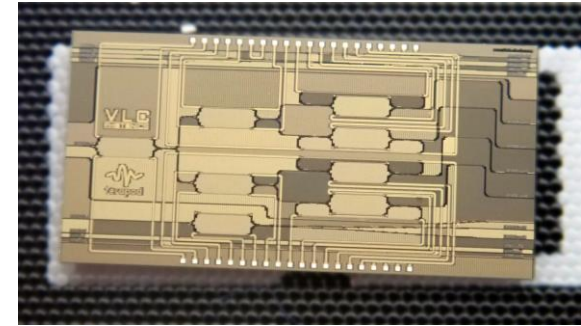
**Japan**  
(12 companies)



# PIC development cycle



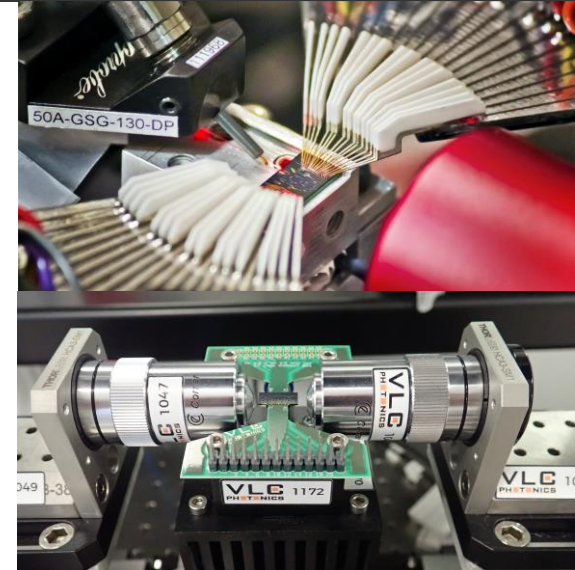
- ❑ **It is still critical to do extensive component / circuit characterization when validating PIC designs in engineering.**
  - To validate fabrication process and its tolerances through sensitivity analysis (**specially needed in photonics**).
  - To confirm the intended layout functionality, and feedback the designs for statistical modelling.
  - To sort out known good dies (KGD) and provide feedback on foundry yield, for accelerating ramp up.
  
- ❑ **When moving to PIC volume production, scalability becomes an issue:**
  - Functional circuit testing is still required beyond fab metrology and PCM.
  - Need fast and low cost Wafer/KGD sorting/binning before packaging.
  - Significant CAPEX for parallelization, engineering and setup time required.



# Characterization & Testing facilities

## Two clean room labs (ISO class 6 and 8) with:

- ❑ Optical microscopes & SEM for detailed visual inspection
- ❑ Optical (vertical and edge light coupling) and electrical probing:
  - ❑ 5 semi-automated bare die characterization setups
  - ❑ 1 manual electrical wafer tester
  - ❑ 2 fully automated opto-electronic wafer testers
- ❑ Electrical measurement instrumentation for DC and RF signal testing up to 110 GHz and optical equipment to work from visible (400 nm) to mid-IR (up to 5  $\mu\text{m}$ ).
- ❑ Test assembly:
  - ❑ 1 manual & 1 automated wire-bonder
  - ❑ 1 flip-chip tool



## DEVICES

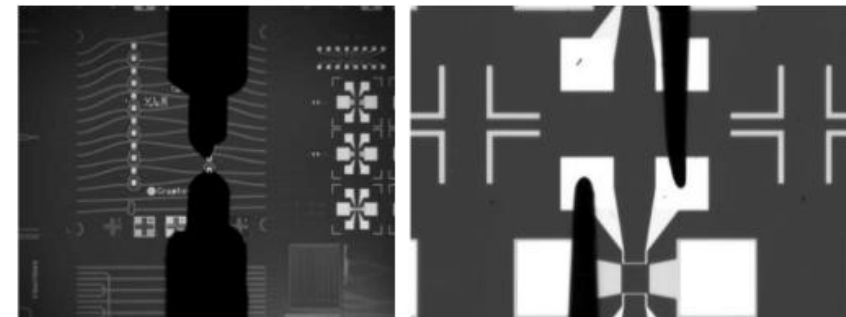
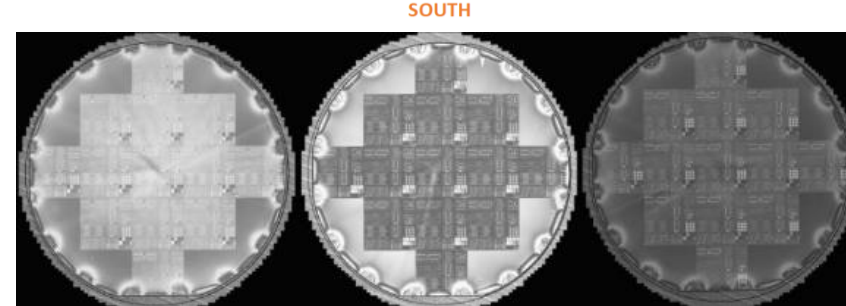
Our Wafer Level Testers are adapted to work with:

- Wafers, up to 12 inches.
- Bars, up to 12 inches.
- Diced chips (from 1mm x 1mm above).

## ELECTRICAL PROBING

We have capabilities to do electrical testing from all 4 sides of the chip.

- DC Probing
  - Single needle.
  - MCM (Multi Contact Needles). Std. pitch: 100um, 150um and 250um.
- RF Probing
  - GSG. Std. pitch: 60um.
  - Up to 110GHz measurements.





## OPTICAL PROBING

We have capabilities to do optical testing from **West** and **East** sides of the chip. North and South stages just can be used for electrical probing.

### Vertical coupling (All types of devices)

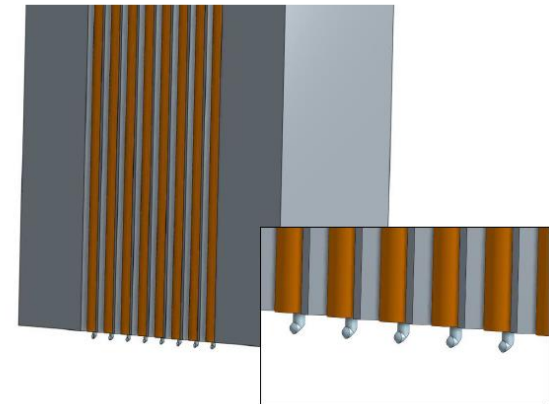
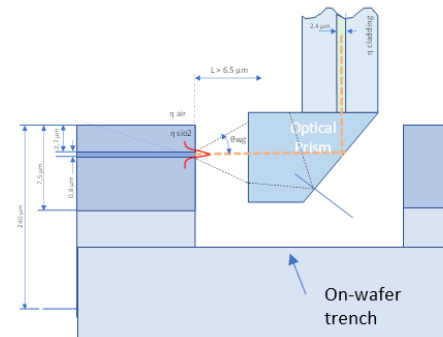
- Cleaved fibers
- Fiber Arrays (FA)
- Leadless Fiber (Leadless FA)
- With or without Anti Reflection Coating (ARC)
- With automatic polarization control.

### Edge coupling (Bars and Diced chips)

- Cleaved fibers & Lensed Fibers
- Fiber Arrays (FA)
- Fiber Arrays with lensed fibers (Lensed FA)
- With or without Anti Reflection Coating (ARC)
- With automatic polarization control.

### Extra: Edge coupling with periscopes

- For non-diced wafers with trenches.



## OPTICAL PROBING

We have capabilities to do optical testing from **West** and **East** sides of the chip.

### Vertical coupling (All types of devices)

- Cleaved fibers
- Fiber Arrays (FA)
- Leadless Fiber (Leadless FA)
- With or without Anti Reflection Coating (ARC)
- With automatic polarization control.

- We are open to evaluate all kinds of projects.
- We did even adapted our WLTs to use **integrated lasers** as optical probes.

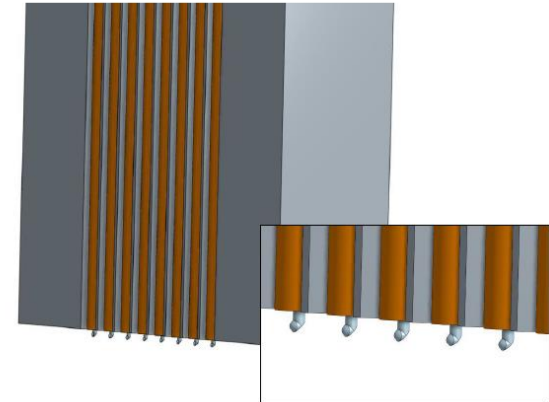
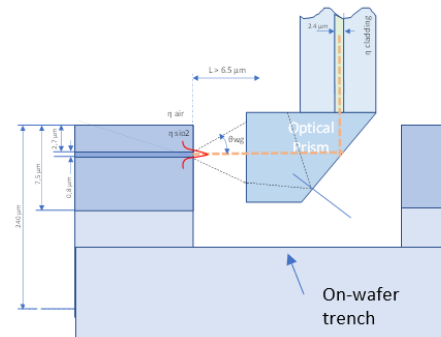


### Edge coupling

- Cleaved fibers & Lensed Fibers
- Fiber Arrays (FA)
- Fiber Arrays with lensed fibers (Lensed FA)
- With automatic polarization control.

### Extra: Edge coupling with periscopes

- For non-diced wafers with trenches.

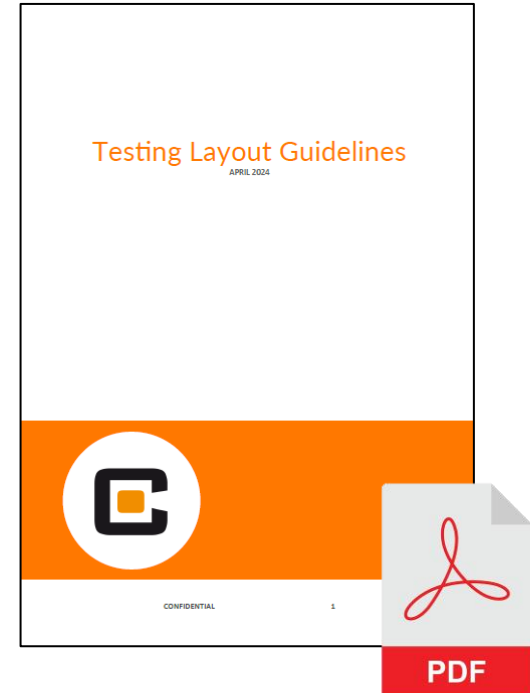


- Testing layout guidelines.**

We gathered all the specs to be required by the chip design to be tested in a PDF manual.  
Feel free to ask for it.

- Assembly Design Kits (ADKs)**

Available for some foundries and EDA software frameworks.  
Compatible with test and packaging requirements.



Parameter	Minimum requirement	Recommended
T: Optical ports pitch	127µm / 250 µm	127µm / 250 µm
U: Optical ports clearance area	1250 µm (for standard FA)	1500 µm
V: Optical ports vertical coupling angle	7° to 13°	10°
W: Vertical safety distance	30 µm	

Parameter	Minimum requirement	Recommended
P: Optical ports pitch	50 µm	127µm / 250 µm
Q: Optical ports clearance area	50 µm	250 µm
R: Optical ports vertical coupling angle	7° to 13°	10°
S: Vertical safety distance	30 µm	

## Examples of previous projects:

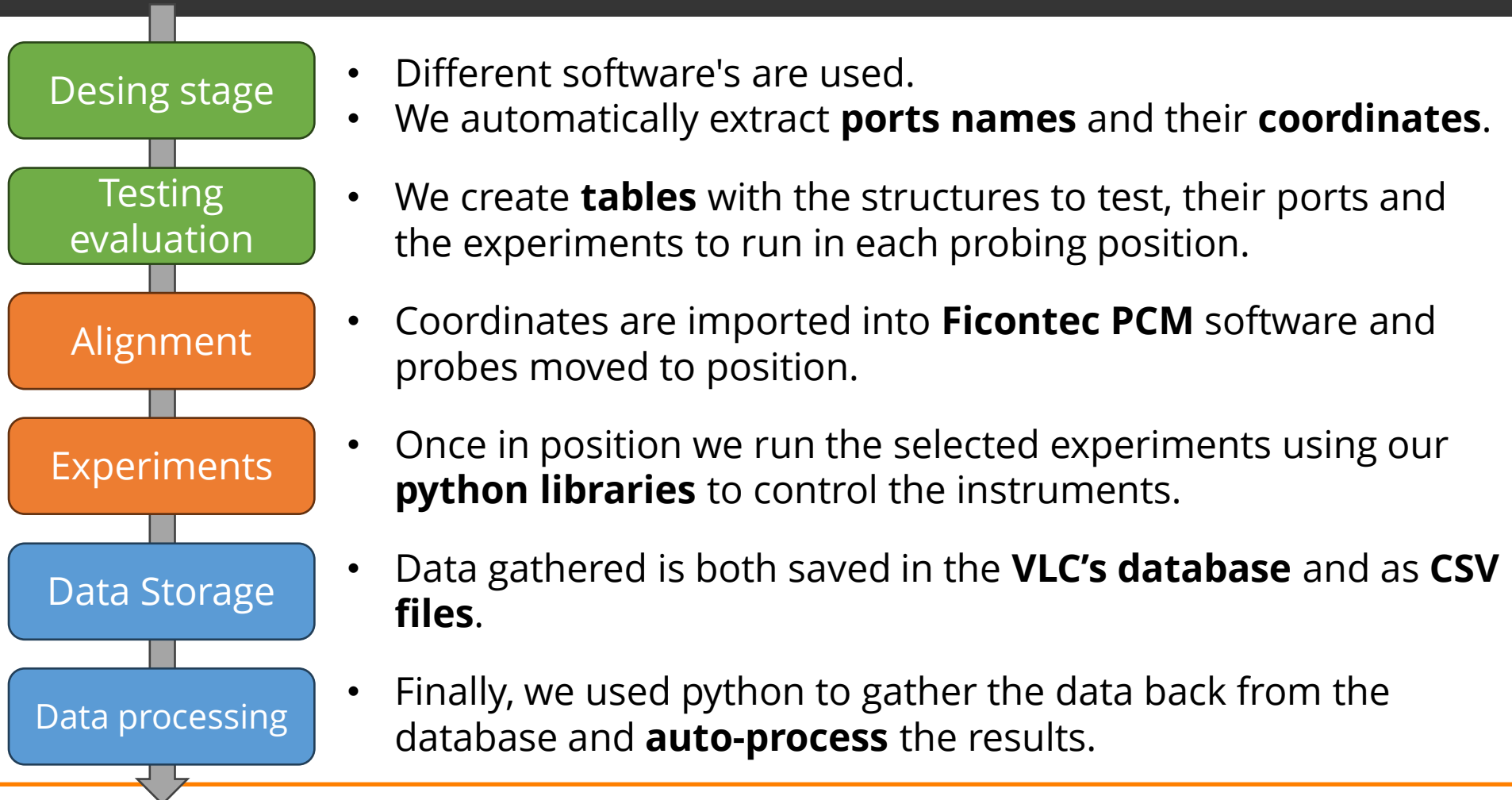
DUT	Structures	Measurements
Six 6" wafers, >300 dies	>5k	~50k
Two 8" wafers, >1800 dies	>14.5k	~58k
>50 dies	>140	>31k

## Example times

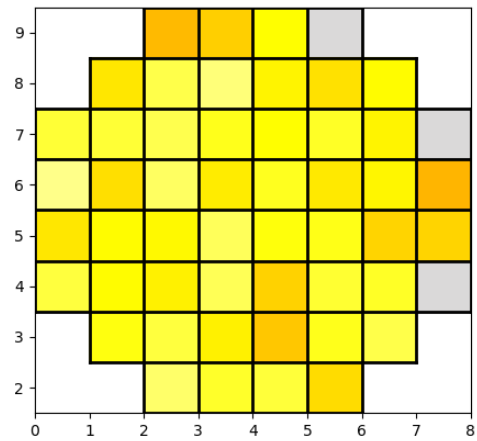
Probing time: 4 s  
Measurement time: 1 s  
# measurements: 50k

**TOTAL TIME = ~3 days**

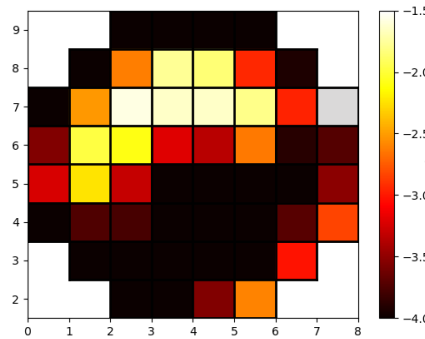
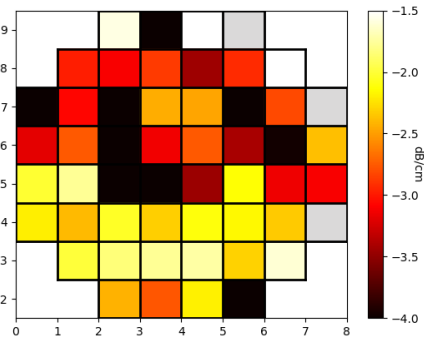
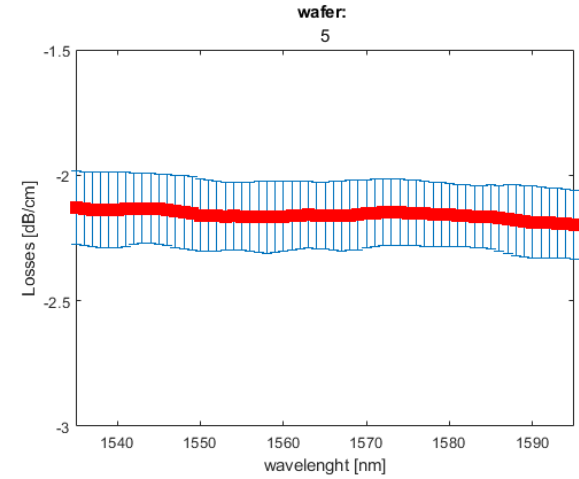
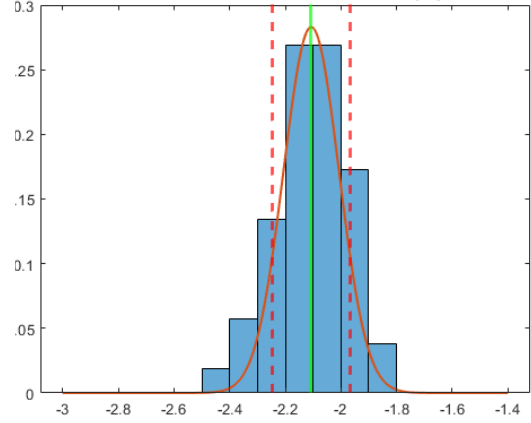
- Fast probing and trace acquisition times are essential when scaling up.
- Smart characterization plan and execution is a must for insightful but time-practical test campaign.
- We developed a tool to estimate the testing times considering the different types of probing we offer and the different experiments we have in our portfolio.



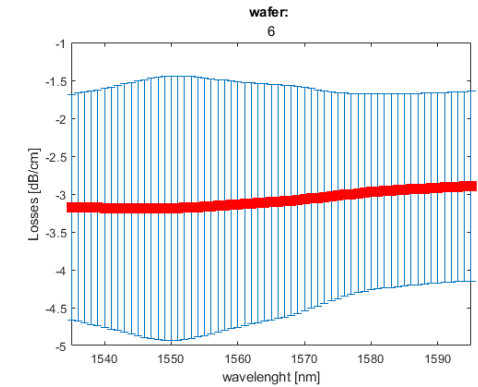
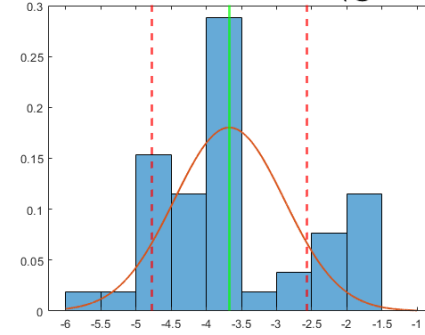
# Process control and yield analysis



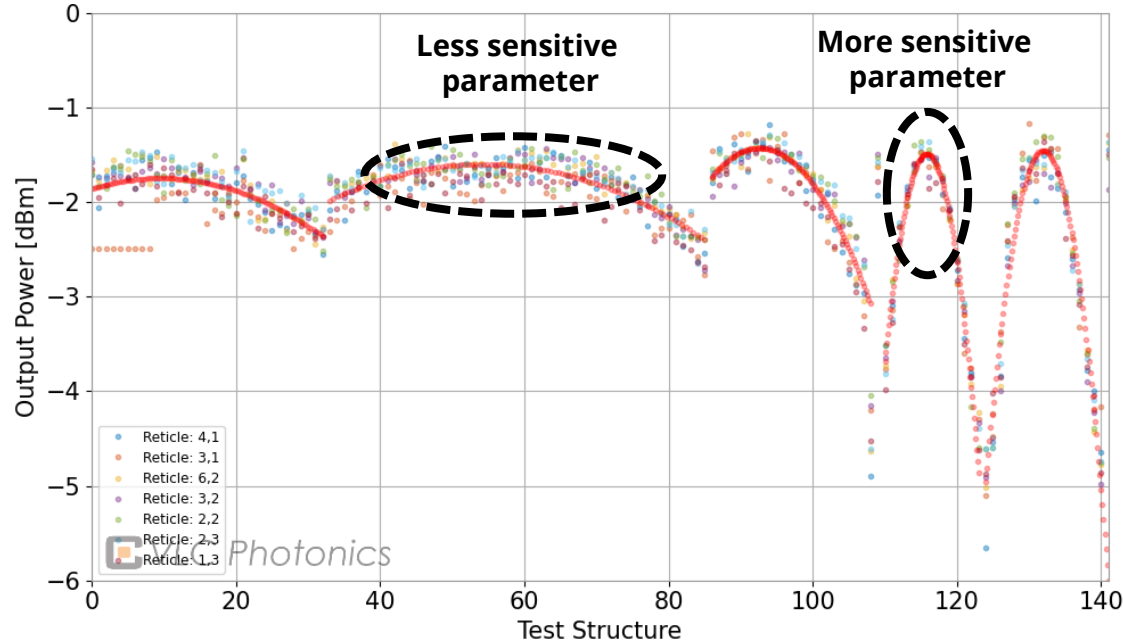
Wafer: 5 Mean = -2.107. SD = 0.141 (@1550 nm)



Wafer: 2 Mean = -3.672. SD = 1.107 (@1550 nm)



## Example of design parameters sweep over 140 test structures in 7 reticles



- Repeatability of bare die measurements with manual alignment is poor ( $>0.5$  dB).
- WLT ensures that alignment and trace acquisition are done automatically with minimal variations (mechanical, thermal etc.)



- **Lightwave Component Analysers (LCA's) for parametric testing of devices like high speed modulators in transceivers.**
  - Up to 110 GHz turn-key test system for optical RX and TX
  - Suitable for die and wafer level testing
  - Return to zero and nonreturn-to-zero (RZ / NRZ) and pulse amplitude modulation (PAM) formats
  - S-parameter testing over the full 1260 nm to 1620 nm range



# Thank you for your attention!

**VLC**  
**PHOTONICS**  
A Hitachi Group Company



Contact details

---



[info@vlcphotonics.com](mailto:info@vlcphotonics.com)



[www.vlcphotonics.com](http://www.vlcphotonics.com)



[@vlcphotonics](https://twitter.com/vlcphotonics)



[linkedin.com/company/vlc-photonics](https://linkedin.com/company/vlc-photonics)